



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

**APPLICANT:** Gormley et al. **GROUP:** 2822  
**SERIAL NO:** 10/617,427 **EXAMINER:.** P.Perkins  
**FILED:** 07/11/03 **Confirmation No.:** 3233  
**FOR:** METHOD FOR FORMING A MICRO-MECHANICAL COMPONENT  
IN A SEMICONDUCTOR WAFER, AND A SEMICONDUCTOR WAFER  
COMPRISING A MICRO-MECHANICAL COMPONENT FORMED THEREIN

**Mail Stop Amendment**  
**Commissioner of Patents**  
**P.O. Box 1450**  
**Alexandria, VA 22313-1450**

**Attn: Issue Fee**

**TRANSMITTAL OF FORMAL DRAWINGS**

Applicant submits herewith new drawing(s) for this application. Attached please find four  
(4) sheets of formal drawings for this application.

Respectfully submitted,

Matthew E. Connors  
Registration No. 33,298  
Gauthier & Connors LLP  
225 Franklin Street, Suite 2300  
Boston, Massachusetts 02110  
Telephone: (617) 426-9180  
Extension 112

---

I hereby certify that this paper (along with any paper referred to as being attached or enclosed) is being deposited with the United States Postal Service on the date shown below with sufficient postage as first class mail in an envelope addressed to the Commissioner of Patents and Trademarks, P.O. Box 1450, Alexandria, VA 22313-1450, Mail Stop: Issue Fee

Deborah M. Costello

Date: 3-13-04